

Title (en)

CONTROLLED VACUUM ARC MATERIAL DEPOSITION, METHOD AND APPARATUS.

Title (de)

VERFAHREN UND VORRICHTUNG ZUM GESTEUERTEN AUFBRINGEN VON MATERIAL MITTELS LICHTBOGEN IM VAKUUM.

Title (fr)

DEPOSITION REGULEE DE MATERIAU PAR ARC SOUS VIDE, PROCEDE ET APPAREIL.

Publication

EP 0174977 A4 19870212 (EN)

Application

EP 85901674 A 19850227

Priority

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Abstract (en)

[origin: WO8503954A1] A method and apparatus for vacuum arc deposition of material on a surface of an object (32), uses a vacuum chamber (12) accomodating the active surface of the cathode (24) and an anode (34). A power supply connected to the anode (34) and cathode (24) establishes an electric arc. The track of the arc is controlled with a magnetic field established with a permanent magnet (56) that is moved in a closed path relative to the cathode. A solenoid (68) modifies the main magnetic field produced on the active surface of the cathode (24).

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IPC 8 full level

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Citation (search report)

- [X] SOVIET INVENTIONS ILLUSTRATED, week D15, 20th May 1981; & SU-A-711 787 (L.P. SABLEV) 17-06-1978
- See references of WO 8503954A1

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